

**RECEIVED**  
**CENTRAL FAX CENTER****APR 29 2005****IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Ilyun-Jae Kim, et al. )  
Serial No.: 10/663,081 ) Group Art Unit:  
Filed: September 16, 2003 ) 1756  
For: MASK FOR POLYCRYSTALLIZATION AND )  
METHOD OF MANUFACTURING THIN FILM )  
TRANSISTOR USING )  
POLYCRYSTALLIZATION MASK )

VIA FACSIMILE TO 1-703-872-9306  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT UNDER 37 C.F.R. §1.111**

Sir:

In response to the Office action of November 29, 2004, Applicants request reconsideration in view of the following amendments and remarks for entry in the above-identified application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.

I hereby certify that this correspondence, consisting of 9 total pages, was facsimile transmitted to the United States Patent Office (Fax No. 1-703-872-9306) on	
April 29, 2005 (Date of Deposit)	
Patricia A. Hart (Name of Person Mailing Paper)	
<i>Patricia A. Hart</i> Signature	04/29/05 Date

10/663,081  
YOM-0060

1